

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A plasma generating electrode comprising at least a pair of electrodes disposed opposite to each other and capable of generating plasma upon application of voltage between the electrodes;

at least one of the pair of electrodes including a ~~plate-like~~plate-shaped ceramic body as a dielectric and a plurality of conductive films disposed inside the ceramic body without overlapping with one another and each conductive film of the plurality of conductive films having a plurality of through-holes formed through the conductive film in its thickness direction in a predetermined arrangement pattern, the through-holes having a cross-sectional shape including an arc shape along a plane perpendicular to the thickness direction, ~~an~~the arrangement pattern of the through-holes formed in at least one of the conductive films being different from the arrangement pattern of the through-holes formed in another of the other conductive ~~film~~films, the plasma generating electrode being capable of simultaneously generating different states of plasma upon application of voltage between the pair of electrodes due to the different arrangement patterns of the through-holes in the conductive films of the at least one of the pair of electrodes.

2. (Currently Amended) A plasma generating electrode comprising at least a pair of electrodes disposed opposite to each other and capable of generating plasma upon application of voltage between the electrodes,

at least one of the pair of electrodes including a ~~plate-like~~plate-shaped ceramic body as a dielectric and at least one conductive film disposed inside the ceramic body and having a plurality of through-holes formed through the conductive film in its thickness direction in two or more different arrangement patterns, the through-holes having a cross-

sectional shape including an arc shape along a plane perpendicular to the thickness direction, the plasma generating electrode being capable of simultaneously generating different states of plasma upon application of voltage between the pair of electrodes due to the different arrangement patterns of the through-holes in the conductive film in the at least one of the pair of electrodes.

3. (Currently Amended) The plasma generating electrode according to claim 1, wherein the through-holes have a circular cross-sectional shape along ~~a~~ the plane perpendicular to the thickness direction.

4. (Currently Amended) The plasma generating electrode according to claim 1, wherein at least one of the conductive films includes a metal differing from that of ~~the~~ another conductive film as a major component.

5. (Currently Amended) The plasma generating electrode according to claim 1, wherein at least one of the conductive ~~film~~ films includes at least one metal selected from the group consisting of tungsten, molybdenum, manganese, chromium, titanium, zirconium, nickel, iron, silver, copper, platinum, and palladium as a major component.

6. (Currently Amended) The plasma generating electrode according to claim 1, wherein at least one of the conductive ~~film~~ films is disposed inside the ceramic body by screen printing, ~~calendar~~ calendar rolling, spraying, chemical vapor deposition, or physical vapor deposition.

7. (Previously Presented) A plasma generation device comprising the plasma generating electrode according to claim 1.

8. (Original) An exhaust gas purifying device comprising the plasma generation device according to claim 7 and a catalyst, the plasma generation device and the catalyst being disposed in an exhaust system of an internal combustion engine.

9. (New) The plasma generating electrode according to claim 2, wherein the through-holes have a circular cross-sectional shape along the plane perpendicular to the thickness direction.

10. (New) The plasma generating electrode according to claim 2, wherein the at least one conductive film includes a plurality of conductive films, and at least one of the conductive films includes a metal differing from that of another conductive film as a major component.

11. (New) The plasma generating electrode according to claim 2, wherein the at least one conductive film includes at least one metal selected from the group consisting of tungsten, molybdenum, manganese, chromium, titanium, zirconium, nickel, iron, silver, copper, platinum, and palladium as a major component.

12. (New) The plasma generating electrode according to claim 2, wherein the at least one conductive film is disposed inside the ceramic body by screen printing, calendar rolling, spraying, chemical vapor deposition, or physical vapor deposition.

13. (New) A plasma generation device comprising the plasma generating electrode according to claim 2.

14. (New) An exhaust gas purifying device comprising the plasma generation device according to claim 13 and a catalyst, the plasma generation device and the catalyst being disposed in an exhaust system of an internal combustion engine.